DS - 07/12/2 202ECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

Title of Invention

FEATURE DIMENSION DEVIATION CORRECTION SYSTEM, METHOD AND PROGRAM PRODUCT

Application Number:

Confirmation Number:

First Named Applicant:

David Horak

Attorney Docket Number:

FIS920040187US1

Art Unit:

Examiner:

Search string:

(6727108 or 6701206 or 6643008 or 6707562 or 6614540 or 6639663 or 6625497

or 5739909 or 20040005507).pn

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
MDM	1	6727108	2004-04-27	Eriguchi, et al.			
MDM	2	6701206	2004-03-02	Markle, et al.			
MDM	3	6643008	2003-11-04	Stirton, et al.			
MDM	4	6707562	2004-03-16	Lensing			
MDM	5	6614540	2003-09-02	Stirton			
MDM	6	6639663	2003-10-28	Markle, et al.			
MDM	7	6625497	2003-09-23	Fairbairn, et al.			
MDN	8	5739909	1998-04-14	Blayo, et al.	·		

US Published Applications

Note: Applicant is not required to submit a paper copy of cited US Published Applications

init Cite.No.	Pub. No.	Date	Applicant	Kind	Class	Subclass
MDM 1	20040005507	2004-01-08	Lakkapragada, et al			

Signature

Examiner Name	Date			
/Michael Masinick/	01/22/2007			

PTO/SB/08B (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Und	the Paperwork Red	uction /	Act of 1995, no persons are	required to respond to a collection	n of information unless it contains a valid OMB condoi in	unioe	
ostitute for form 1449B/PTO				Complete if Known			
TOFO	RMATION	N DI	SCLOSURE	Application Number	10/710, 447		
STAT	FMENT	3Y /	APPLICANT	Filing Date	7-12-04		
0.7				First Named Inventor	David V. Horak et al.		
				Group Art Unit			
(use as many sheets as necessary)				Examiner Name			
Sheet	1	of	1	Attorney Docket Number	FIS920040187US1		

		OTHER PRIOR ART NON PATENT LITERATURE DOCUMENTS	
xaminer nitials*	Cite No.1	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T²
MDM		BAUM, C.C. et al., "Scatterometry for Post-Etch Polysilicon Gate Metrology," Proceedings of the SPIE – The International Society for Optical Engineering Conference, Vol. 3677, Pt. 1-2, pp. 148-158.	
MDM		AL-ASSAAD, R.M. et al., "Profile Parameter Accuracy Determined from Scatterometric Measurements," Proceedings of the SPIE – The International Society for Optical Engineering Conference, Vol. 4692, pp. 17-28.	
MDM		DREGE, EMMANUEL M. et al., "Linearized Inversion of Scatterometric Data to Obtain Surface Profile Information," Optical Engineering, Vol. 41, No. 1, pp. 225-236.	
	\vdash	·	

Examiner Signature	/Michael Masinick/	Date Considered	01/22/2007

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

Burden Hour Statement: This form is estimated to take 2.0 hours to complete. Time will vary depending upon the needs of the individual case Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.